

KEY FEATURES

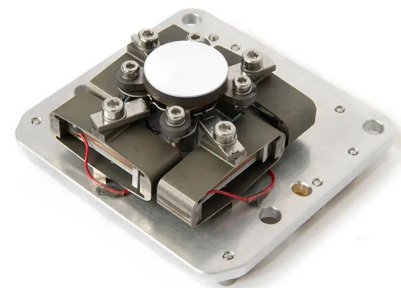
- > Compact & High Dynamic
- > Low capacitance & low power consumption
- > Symetric push pull mechanical and electrical design
- > Strain Gages sensor (SG)
- > High resonance frequency
- > Rugged to vibrations and shocks
- > Vacuum compatible

RELATED PRODUCTS

- > CCB μ 20
- > CCB μ 40

AVAILABLE OPTIONS

- > Vacuum



PARAMETER	TYPICAL VALUE	UNIT
> Quasistatic performances ⁽¹⁾		
Nominal stroke in open loop	18	mrاد
Nominal stroke in close loop	16	mrاد
Resolution ⁽²⁾	< 20	μrad
> Dynamic performances		
Loaded Blocked - free resonance frequency ⁽³⁾	> 700	Hz
> Mirror substrates and coatings options		
Substrates options	SiC and SiO2	
Substrate size / clear aperture		
SiO2 substrate	15mm diameter CA > 13mm	
SiC substrate	17 mm diameter CA > 15.5 mm	
Coating options	Siver and Hybrid coating on SiC substrate UV Enhanced Aluminum on SiO2 substrate Custom substrate & Coating on demand	
> Driving		
Voltage range	-20 to +150	V
Capacitance ⁽⁴⁾	2.8	μF

ANNOTATIONS

Guaranted in labs environment. A misused can lead to temporary or definitive alterations of properties. Contact CEDRAT TECHNOLOGIES prior using actuators under non standard technical conditions

(1) AC voltage, full range @ 1 Hz at Ambient Temperature in open loop

(2) With close loop based on strain gages

(3) Blocked-free: The actuator is fixed to a mechanical support assumed infinitely stiff

(4) Per axis, quasistatic excitation, free-free, +/- 20%, at 1 V RMS without mirror